

BUFFER APPARATUS AND THIN FILM DEPOSITION SYSTEM

ABSTRACT OF THE DISCLOSURE

A buffer apparatus and a thin film deposition system are provided. The buffer apparatus is connected between a liquid material supply apparatus and a deposition machine. The buffer apparatus includes a container and a baffle. The container is used for containing a liquid material supplied from the liquid material supply apparatus. The top of the container has an input hole and an output hole. The baffle is disposed in the container and located under the input hole.

10 FIG. 1